ABSTRACT

A wafer holder A1 holds wafers W aligned in a first direction x with surfaces facing each other. The wafer holder A1 includes two groove rows 4 each including holding grooves 40 aligned in the first direction x, and spaced apart from each other in a second direction y perpendicular to the first direction x. Each holding groove 40 is open on one side and at least partially closed on the other side in a third direction z perpendicular to the first direction x and the second direction y, and includes a wide portion 401 and a narrow portion 402. The narrow portion 402 is located on an inner side in the second direction y and on the other side in the third direction z relative to the wide portion 401. At respective ends on the other side in the third direction z, a width X2 of the narrow portion 402 in the first direction is smaller than a width X1 of the wide portion 401 in the first direction. Such a configuration allows wafers to be more appropriately aligned and held.